IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applica	ation of:]	HAGELIN et al.	Confirmation	on No.:	To be assigned
Serial 1	No.:	•	Γo be assigned	Art Unit:	2872	
Filed:		•	July 25, 2003	Examiner:	James Phan	
For:]	Apparatus and Method for Optical Raster-Scanning in a Micromechanical System	Attorney Do	ocket No.:	9785-0008-999
			INFORMATION DISCLOSUI	RE STATEN	IENT	
P.O. B	issioner: ox 1450 dria, VA		Patents 313-1450			
Sir:						
subject	ed certain U.S. par	n inf tent	or with the duty of disclosure provision or mation which the Examiner may correspond to the examination of the application.	sider materia	al to the exam	nination of the
1.	Enclosi	ures	accompanying this Information Disclo	sure Stateme	nt are:	
	1a.	\boxtimes	A list of all patents, publications, apple consideration by the office.	lications, or o	other informa	tion submitted for
	1b.	Αl	egible copy of:			
			Each U.S. patent application publication	on and U.S.	and foreign p	atent;
			Each publication or that portion which	n caused it to	be listed on	the PTO-1449;
		the	For each cited pending U.S. application claims, and any drawing of the application sed it to be listed on the PTO-1449 income.	ation, or porti	on of the app	lication which
			all other information or portion which	caused it to	be listed on t	he PTO-1449.
	1c.		An English language copy of search rapplication or PCT International Search		a counterpar	t foreign
	1d.		Explanations of relevancy (ATTACH abstracts of the non-English language			iglish language
2.		Thi	s Information Disclosure Statement is Within three months of the filing date continued prosecution application und	of a national		
			Within three months of the date of ent §1.491 in an international application:		onal stage as	set forth in

		Before the mailing of the first Office action on the merits;
		Before the mailing of a first Office action after the filing of a request for continued examination under §1.114.
3.		This Information Disclosure Statement is filed under 37 C.F.R. §1.97(c) after the period specified in 37 C.F.R. §1.97(b), but before the mailing date of any of a final action under 37 C.F.R. §1.113, a notice of allowance under 37 C.F.R. §1.311 or an action that otherwise closes prosecution in the application.
		(Check either Item 3a or 3b)
	3a.	☐ The Certification Statement in Item 5 below is applicable. Accordingly, no fee is required.
	3b.	☐ The \$180.00 fee set forth in 37 C.F.R. §1.17(p) in accordance with 37 C.F.R. §1.97(c) is: ☐ enclosed
		to be charged to Pennie & Edmonds LLP Deposit Account No. 16-1150.
		(Item 3b to be checked if any reference known for more than 3 months)
4.		This Information Disclosure Statement is filed under 37 C.F.R. §1.97(d) after the period specified in 37 C.F.R. §1.97(c), but on or before the date of payment of the issue fee.
		The \$180.00 fee set forth in 37 C.F.R. §1.17(p) is: — enclosed. — to be charged to Pennie & Edmonds LLP Deposit Account No. 16-1150.
	The C	Certification Statement in Item 5 below is applicable.
5.		Certification Statement (applicable if Item 3a or Item 4 is checked)
		(Check either Item 5a or 5b)
	5a.	☐ In accordance with 37 C.F.R. §1.97(e)(1), it is certified that each item of information contained in this Information Disclosure Statement was first cited in a communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this Information Disclosure Statement.
	5b.	In accordance with 37 C.F.R. §1.97(e)(2), it is certified that no item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application and, to the knowledge of the undersigned after making reasonable inquiry, was known by any individual designated in 37 C.F.R. §1.56(c) more than three months prior to the filing of this Information Disclosure Statement.
6.	\boxtimes	This application is a continuation application under 37 C.F.R. §1.60 or §1.53(b) or (d).
		(Check appropriate Items 6a, 6b and/or 6c)
	6a.	A Petition to Withdraw from issue under 37 C.F.R. §1.313(b)(5) is concurrently filed herewith.

	6b.	Copies of publications listed on Form PTO-1449 from prior application Serial No. 10/052,148, filed on January 16, 2002, of which this application claims priority under 35 U.S.C. §120, are not being submitted pursuant to 37 C.F.R. §1.98(d).
	6c.	Copies of the publications listed on Form PTO-1449 were not previously cited in prior application Serial No. , filed on , and are provided herewith.
7.		This is a Supplemental Information Disclosure Statement. (Check Item 7a)
	7a.	This Supplemental Information Disclosure Statement under 37 C.F.R. §1.97(f) supplements the Information Disclosure Statement filed on . A bona fide attempt was made to comply with 37 C.F.R. §1.98, but inadvertent omissions were made. These omissions have been corrected herein. Accordingly, additional time is requested so that this Supplemental Information Disclosure Statement can be considered as if properly filed on .
8.		In accordance with 37 C.F.R. §1.98, a concise explanation of what is presently understood to be the relevance of each non-English language publication is:
		(Check Item 8a, 8b, or 8c)
	8a.	satisfied because all non-English language publications were cited on the enclosed English language copy of the PCT International Search Report or the search report from a counterpart foreign application indicating the degree of relevance found by the foreign office.
	8b.	set forth in the application.
	8c.	enclosed as an attachment hereto.
9.	\boxtimes	The Commissioner is authorized to charge any additional fee required or credit any overpayment for this Information Disclosure Statement and/or Petition to Pennie & Edmonds LLP Deposit Account No. 16-1150.
10.		No admission is made that the information cited in this Statement is, or is considered to be, material to patentability nor a representation that a search has been made (othe than a search report of a foreign counterpart application or PCT International Search Report if submitted herewith). 37 C.F.R. §§1.97(g) and (h).
Date:	July 2	Respectfully submitted, 25, 2003 Respectfully submitted, 24,615 Francis E. Morris for Gary S. Williams PENNIE & EDMONDS LLP 3300 Hillview Avenue Palo Alto, California 94304 (650) 493-4935

LIST OF REFERENCES CITED BY APPLICANT

(Use several sheets if necessary)

ATTY, DOCKET NO. : 9875-0008-999	APPLICATION NO. To be assigned		
APPLICANT			
Hagelin et al.			
FILING DATE	GROUP		
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			July 25, 2003		.2872		
 	· · · · · · · · · · · · · · · · · · ·	U	S. PATENT DOCUMENTS	·	·		
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILIN IF APP	G DATE
	5,867,297	2/1999	Kiang et al.				
	5,629,790	5/1997	Neukermans et al.		<u> </u>	<u> </u>	
	5,408,352	4/1995	Peng				
	4,317,611	3/1982	Peterson				
	5,361,158	11/1994	Tang				
	5,998,906	12/1999	Jerman et al.	310			
		FOR	EIGN PATENT DOCUMENTS				
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANS	SLATIO
						YES	NK.
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	OTHER	DEEEDENCES (Including Author, Title, Date, Pertinent Pages, Et]	1	<u> </u>
			er Coupling Module Using a Micromachined Align		Conforma		
			eries, Vol. 15, pp.245-250, Baltimore, MD, May 1		Conterence	e on La	sers
			for Positioning Optical Components", J of Microe.		ical System	s, 5 (3):	159
	(1996).						
	1	Daneman et al., "Linear Virbromotor-Actuated Micromachined Microreflector for Integrated Optical Systems", Solid-State Sens					
	and Actuator Workshop, Hilton Head, SC, June 2-6 1996.						
	*		icon Micromotors for Optical Scanning Applicatio	ns", <i>Solid-Sta</i>	ite Sensor a	nd Acti	uato
	Workshop, pp. 234-238, Hilton Head, SC, June 13-16, 1994. Kiang et al., "Electrostatic Combdrive-Actuated Micromirrors for Laser-Beam Scanning and Positioning", J of						
		ic Combdrive-Ac	tuated Micromirrors for Laser-Beam Scanning an	d Positioning	". J of		
			_	d Positioning	", J of		. .
	Kiang et al., "Electrostat Microelectromechanical	Systems, 7(1):2	_			uctor La	ser
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci	Systems, 7(1):2	7-37, March 1998.	xternal-Cavity	Semicondu		ser:
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach	Systems, 7(1):2' sion Si-Micromad Electro-Optic	7-37, March 1998.	xternal-Cavity Baltimore, MI	Semicondo D, May 1995	5	_
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach 1709, December 1996.	Systems, 7(1):2' sion Si-Micromac and Electro-Optic nined Polysilicon	7-37, March 1998. chined Micromirrors with On-Chip Actuation for E s, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers", IEEE Pho	xternal-Cavity Baltimore, MI tonics Techno	Semicondo D, May 1999 ology Letter	5. s, 8(12)	:170
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach 1709, December 1996.	Systems, 7(1):2' sion Si-Micromac and Electro-Optic nined Polysilicon cromachined Mic	7-37, March 1998. chined Micromirrors with On-Chip Actuation for Es, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers*, IEEE Phoromirrors with Integrated High-Precision Actuator	xternal-Cavity Baltimore, MI tonics Techno	Semicondo D, May 1999 ology Letter	5. s, 8(12)	:170
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach 1709, December 1996. Kiang et al., "Silicon-Mic Lasers", IEEE Photonic	Systems, 7(1):2' sion Si-Micromac and Electro-Optic nined Polysilicon cromachined Mic s Technology Lei	7-37, March 1998. chined Micromirrors with On-Chip Actuation for Es, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers*, IEEE Phoromirrors with Integrated High-Precision Actuator	xternal-Cavity Baltimore, MI tonics Techno	Semicondo D, May 1999 ology Letter	5. s, 8(12)	:170
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach 1709, December 1996. Kiang et al., "Silicon-Mic Lasers", IEEE Photonic	Systems, 7(1):2' sion Si-Micromacind Electro-Optic nined Polysilicon cromachined Mic s Technology Lected Hinges", S	7-37, March 1998. chined Micromirrors with On-Chip Actuation for E s, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers", IEEE Pho romirrors with Integrated High-Precision Actuator tters, 8(1):95-97 (1996).	xternal-Cavity Baltimore, MI tonics Technology s for External	Semicondu D, May 1995 ology Letter -Cavity Sem	5. s, 8(12) nicondu	:170
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach 1709, December 1996. Kiang et al., "Silicon-Mic Lasers", IEEE Photonic. Pister et al., "Microfabric Solgaard, O., "High-Res IEEJ/SAMS 1997 Intern	Systems, 7(1):2' sion Si-Micromac and Electro-Optic nined Polysilicon cromachined Mic s Technology Lected Hinges", Si solution Silicon	7-37, March 1998. chined Micromirrors with On-Chip Actuation for E.s., Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers*, IEEE Photomorphisms with Integrated High-Precision Actuator Iters, 8(1):95-97 (1996).	xternal-Cavity Baltimore, MI tonics Techno s for External	Semicondu D, May 1999 ology Letter -Cavity Sem	5. s, 8(12) nicondu	:170
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach 1709, December 1996. Kiang et al., "Silicon-Mic Lasers", IEEE Photonica Pister et al., "Microfabric Solgaard, O., "High-Res IEEJ/SAMS 1997 Interm November 18-21, 1997.	Systems, 7(1):2 sion Si-Micromac and Electro-Optic nined Polysilicon cromachined Mic s Technology Lected Hinges", S colution Silicon Silicon Siliconal Conference	chined Micromirrors with On-Chip Actuation for Es, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers", IEEE Photomirrors with Integrated High-Precision Actuator Itlers, 8(1):95-97 (1996). ensors and Actuators, 33(3):249-256 (1992). purface Micromachined Displays", (invited talk), Technical MEMS and their Applications (MOE)	echnical Dige:	o Semicondu D, May 1995 ology Letter -Cavity Sem st of the IEE	s, 8(12) nicondu	ctor
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers a Kiang et al., "Micromach 1709, December 1996. Kiang et al., "Silicon-Mic Lasers", IEEE Photonics Pister et al., "Microfabric Solgaard, O., "High-Res IEEJ/SAMS 1997 Intern November 18-21, 1997. Solgaard et al., "Optoele	Systems, 7(1):2' sion Si-Micromac and Electro-Optic nined Polysilicon cromachined Mic s Technology Lected Hinges", Sicultion Silicon Stational Conference	7-37, March 1998. chined Micromirrors with On-Chip Actuation for Es, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers", IEEE Photomorphisms with Integrated High-Precision Actuator Iters, 8(1):95-97 (1996). ensors and Actuators, 33(3):249-256 (1992). urface Micromachined Displays", (invited talk), Technical Processing Actuators, 1998).	echnical Dige:	o Semicondu D, May 1995 ology Letter -Cavity Sem st of the IEE	s, 8(12) nicondu	ctor
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers at Kiang et al., "Micromach 1709, December 1996. Kiang et al., "Silicon-Mic Lasers", IEEE Photonical Pister et al., "Microfabrical Solgaard, O., "High-Res IEEJ/SAMS 1997 Interm November 18-21, 1997. Solgaard et al., "Optoele Letters, 7(1):41-43 (199)	Systems, 7(1):2 sion Si-Micromac and Electro-Optic nined Polysilicon cromachined Mic s Technology Lected Hinges", Sicultion Silicon Silicon Silicon Silicon Silicon Silicon Silicon Packagin ectronic Packagin 5).	chined Micromirrors with On-Chip Actuation for Es, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers", IEEE Photomirrors with Integrated High-Precision Actuator Itlers, 8(1):95-97 (1996). ensors and Actuators, 33(3):249-256 (1992). purface Micromachined Displays", (invited talk), Technical MEMS and their Applications (MOE)	echnical Diges MS97), pp. 9-	o Semicondo D, May 1995 ology Letters -Cavity Sem est of the IEE 14, Nara, Ja	s, 8(12) nicondu	ctor
	Kiang et al., "Electrostat Microelectromechanical Kiang et al., "High-Preci Conference on Lasers at Kiang et al., "Micromach 1709, December 1996. Kiang et al., "Silicon-Mic Lasers", IEEE Photonical Pister et al., "Microfabrical Solgaard, O., "High-Res IEEJ/SAMS 1997 Interm November 18-21, 1997. Solgaard et al., "Optoele Letters, 7(1):41-43 (199)	Systems, 7(1):2' sion Si-Micromac and Electro-Optic nined Polysilicon cromachined Mic s Technology Lected Hinges", Sicultion Silicon Silicon Silicon Scational Conference ectronic Packagin 5).	chined Micromirrors with On-Chip Actuation for Es, Technical Digest Series, Vol. 15, pp. 248-249, Microscanners for Barcode Readers", IEEE Photomirrors with Integrated High-Precision Actuator Iters, 8(1):95-97 (1996). Lensors and Actuators, 33(3):249-256 (1992). Lurface Micromachined Displays", (invited talk), Technical MEMS and their Applications (MOE). Long Using Silicon Surface-Micromachined Alignments of Polysilicon Micromirrors for Hybrid Integra	echnical Diges MS97), pp. 9-	o Semicondo D, May 1995 ology Letters -Cavity Sem est of the IEE 14, Nara, Ja	s, 8(12) nicondu	ctor

Lin et al. "Free-Space Micromachined Optical Switches with Submillisecond Switching Time for Large-Scale Optical Crosso IEEE Photonics Technology Letters, Vol. 10, No. 4, April 1998, pp 525-527.	EXAMINER		DATE CONSIDERED
		TEEE PROTOTICS TECHNOLOGY Letters, Vol.	. 10, 140. 4, April 1990, pp 525-527.
	=	·	•
Yasseen et al., "Diffraction Grating Scanners Using Polysilicon Micromotors", <i>Proceedings IEEE Micro Electro Mechanical Systems</i> , pp. 175-180, Amsterdam, The Netherlands, January 1995.			